

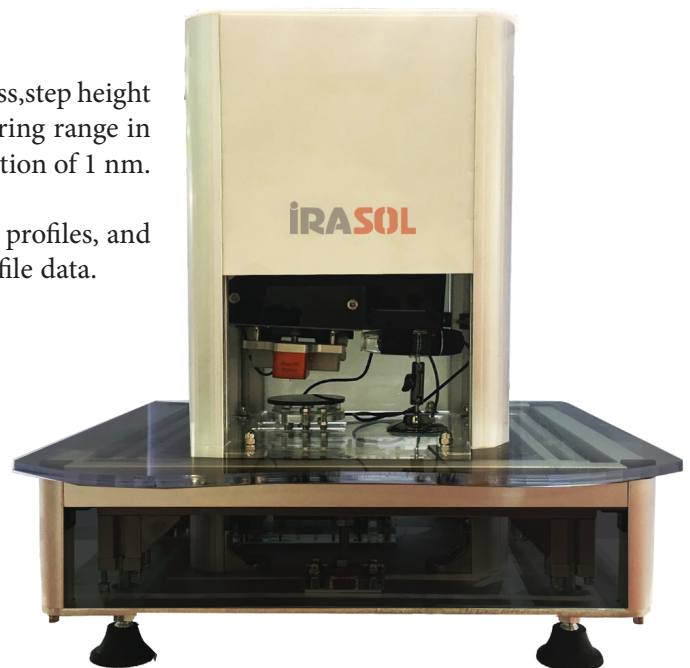
STYLUS PROFILOMETER

High-precision capacitance sensor for Nanometric roughness

OVERVIEW

PFM-6020 is a 1D profilometer for measuring surface roughness, step height and layer thickness. The instrument provides 200 μm measuring range in the z-direction with a precision of 50 nm and a vertical resolution of 1 nm.

The software controls the measurement process, levelizes the profiles, and analyzes the data, reporting roughness values and height profile data.



SPECIFICATIONS

PFM Technical Specifications	
Model	PFM-6020
Measurement technique	Contact stylus profilometry
Profilometry measurement	1-Dimensional surface profile measurement
Tip view camera	640*480 pixel, 50-500X Magnification, Focusable digital camera
Stylus sensor	Capacitive displacement sensor
Sample stage	Linear motion, variable speed
Max. wafer size	120 mm
Scan course	3 cm
Data points per scan	Max. 10000
X-Scan steps	1 μm
Step height precision	50 nm
Maximum measuring vertical range	Optional (100 μm - 2mm)
Vertical resolution	1 nm
Max. sample height	45 mm